

## **IN THE CLAIMS**

1 (Previously Presented).      A method comprising:  
    forming a pore in an insulator;  
    forming a heater in said pore by filling said pore with a conductive material and  
then removing the upper portion of said conductive material;  
    filling the upper portion with a phase change material that extends over said  
insulator;  
    forming a substantially planar upper surface of said phase change material; and  
    forming a substantially planar upper electrode over said substantially planar upper  
surface of said phase change material.

Claims 2 and 3 (Canceled).

4 (Previously Presented).      The method of claim 1 including planarizing the upper  
surface of said insulator.

Claims 5 and 6 (Canceled).

7 (Previously Presented).      The method of claim 1 including patterning and etching  
said phase change material over said insulator.

8 (Original).      The method of claim 7 including forming a T-shaped phase change  
material.

9 (Currently Amended).      The method of claim 3 1 including forming a sidewall  
spacer in said pore.

10 (Currently Amended).      The method of claim 9 wherein forming a heater includes  
~~including~~ depositing metal in said pore after forming said sidewall spacer.

Claims 11-31 (Canceled).